

IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

Applicants: **Davis, et al.**

Case: **7938/ETCH/SILICON/JB**

Serial No.: **10/628,001**

Filed: **July 25, 2003**

Examiner: **Stevenson, Andre C.**

Group Art Unit: **2812**

Confirmation No.: **3943**

Title: **METHOD FOR AUTOMATIC DETERMINATION OF SEMICONDUCTOR
PLASMA CHAMBER MATCHING AND SOURCE OF FAULT BY
COMPREHENSIVE PLASMA MONITORING**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SIR:

AMENDMENT UNDER 37 C.F.R. §1.312

Please enter this amendment and reconsider the claims pending in the application for reasons discussed below. Although the Applicants believe that no fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782 for any fees, including extension of time fees, and any other fees required to make this response timely and acceptable to the Office.